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PATENT

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

INVENTOR: Christopher P. Ausschnitt et al.) EXAMINER:
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)
SERIAL NO.:) ART UNIT:
)
FILING DATE:) DATE: December 4, 2000
)
FOR: SINGLE TONE PROCESS)
 WINDOW METROLOGY)
 TARGET AND METHOD FOR)
 LITHOGRAPHIC)
 PROCESSING)

JC531 U.S. PTO
09/734062
12/11/00



INFORMATION DISCLOSURE STATEMENT

Assistant Commissioner for Patents
Washington, D.C. 20231

Dear Sir:

In accordance with 37 CFR 1.56, 1.97 and 1.98, the following items are made of record to assist the Patent & Trademark Office in its examination of this application and is, in the opinion of the attorney designated below for applicant(s), information relevant to the closest prior art of which that person is aware. The filing of this Information Disclosure Statement shall not be construed as a representation that a search has been made or that no other art than that identified exists.

| <u>PATENT NO.</u> | <u>INVENTOR</u> | <u>ISSUE DATE</u> |
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A copy of each of the foregoing items and Form PTO 1449 are enclosed herewith.

Respectfully submitted,

By:


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CERTIFICATE OF MAILING UNDER 37 CFR 1.10

I hereby certify that, on the date shown below, this correspondence is being deposited with the United States Postal Service in an envelope addressed to the Assistant Commissioner for Patents, Washington, D.C. 20231, as "Express Mail Post Office to Addressee" Mailing Label No. EK140407869US on 12/11/00

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